

03500.015382.



PATENT APPLICATION

AF 1753
JFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: Alan D. Diamond
TAKAHARU KONDO, ET AL.)
: Group Art Unit: 1753
Application No.: 09/866,665)
:
Filed: May 30, 2001)
:
For: SILICON-TYPE THIN FILM)
FORMATION PROCESS, SILICON :
TYPE THIN FILM, AND)
PHOTOVOLTAIC DEVICE : April 6, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated January 6, 2005, please amend the
above-identified application as follows.

I hereby certify that this correspondence is being deposited with the
United States Postal Service as first-class mail in an envelope addressed
to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-
1450 on April 6, 2005
(Date of Deposit)

John A. Krause (Reg. No. 24,613)
(Name of Attorney for Applicants)
Signature April 6, 2005
Date of Signature